ELSEVIER

Thin Solid Films 303 (1997) 302

thin solid films

Author Index of Volume 303

Albella, J.M., 34
Albin, S., 180
Allon-Alaluf, M., 273
Alonso, J.C., 76
Ameziane, E.L., 255
Amouroux, J., 17
Ancey, P., 1
Anderson, W.A., 94
André, J.-J., 107
Aouadi, M.S., 53
Appelbaum, J., 273
Avni, R., 17

Baclez, E., 156
Barelaud, B., 191
Bennouna, A., 255
Bhusari, D.M., 66
Bicho, A., 47
Bied-Charreton, C., 295
Boyer, A., 1
Boyer, L., 200
Brinkmann, M., 107
Burian, A., 143

Cao, W., 89, 146
Caputo, D., 269
Celerier, A., 191
Chahboun, N., 255
Chang, L.H., 94
Chaudhary, S., 128
Chen, C.K., 66
Chen, K.C., 226
Chen, K.H., 66
Chen, L.C., 66
Chuang, T.J., 66
Clarke, G.A., 53
Cobianu, C., 117
Cooper, J.B., 180
Coratger, R., 143
Cosmin, P., 117
Cosset, F., 191
Croitoru, N., 273

Dascalu, D., 117
Da Silva, L.B., 53
De Cesare, G., 269
Dessaux, O., 156
Diamant, R., 76
Ding, M., 213, 282
Dos Santos, M.P., 151

Elazhari, M.Y., 255
Erjavec, B., 4

Faure, J., 295
Fecher, G.H., 58
Fernández-Guasti, M., 76
Ferreira, I., 47
Flueraru, C., 117
Fortunato, E., 47
Fotakis, C., 39
Foucaran, A., 1
Francke, E., 17

García, M., 76
García, M.M., 34
Garnier, F., 207
Gengembre, L., 156
Giani, A., 1
Gómez-Aleixandre, C., 34
Goudmand, P., 156
Grimblot, J., 156
Grünewald, Ch., 58
Gschwind, M., 1
Guessab, S., 200
Guo, D., 282

Haidemenopoulos, G.N., 39
Han, I.-T., 264
Han, S.G., 287
Haro-Poniatowski, E., 76
Havey, K.S., 238
He, T., 213
Hesse, D., 216
Hornyak, G.L., 84
Horowitz, G., 207
Houzé, F., 200
Hozumi, A., 222
Hsieh, C.-D., 232
Huang, X., 213
Huang, Y.F., 66

Ivashchenko, A.I., 292

Jaung, G.J., 226
Jentzsch, Th., 58
Julian, B., 180
Jüpner, H.J., 58

Kang, S.Y., 287
Kashyap, S.C., 128
Kato, M., 196
Kerner, Ia.I., 292
Khedkar, S.P., 167
Kim, H.-Y., 287
Kim, K.H., 287
Kim, M.T., 173
Kim, S.H., 264
Kiosse, G.A., 292
Kleinschmidt, A., 53
Koch, T., 122
Koga, A., 101
Kwon, J.-H., 136

Laaziz, Y., 255
Lang, P., 207
Lécayon, G., 200
Lee, C.-K., 232
Lee, H.J., 287
Lee, J., 173
Lee, J.-W., 264
Lee, M.H., 287
Leray, I., 295
Li, B., 213
Li, Y., 282
Lin, M.C., 66
Liu, W., 89
Lotz, B., 207
Lu, T., 282

Maçarico, A., 47
Maccioni, E., 27
Maharizi, M., 273
Maronchuk, I.Yu., 292
Martin, C.R., 84
Martins, R., 47
Meng, L.-j., 151
Merkel, M., 58
Meyer, S., 207
Miloševv, I., 246
Minarini, C., 269
Miralaï, S.F., 17
Morrison, H., 180
Morvan, D., 17
Mosset, A., 143
Murakami, M., 277
Mutel, B., 156

Navinšek, B., 246
Newton, P., 200
Nichogi, K., 277
Nickel, H., 17
Nicolini, C., 27
Noël, S., 200
Nunes, R., 47

Oelsner, A., 58
Onishi, H., 101
Osborne, N.R., 53
Ostertag, Ch., 58
Outzourhit, A., 255

Palma, F., 269
Pandya, D.K., 128
Pansu, R., 295
Park, Y.S., 264
Parsons, R.R., 53
Pascal-Delannoy, F., 1

Radhakrishnan, S., 167
Ram, M.K., 27
Ramiro-Bargueño, J., 255

Sánchez, O., 34
Schönhense, G., 58
Seidman, A., 273
Senz, St., 216
Shao, X., 213
Shibagaki, S., 101
Shirakawa, Y., 101
Sieber, H., 216
Singh, K.J., 128
Song, P., 180
Sonoda, T., 196
Straupé, C., 207
Strehblow, H.-H., 246
Sun, G., 282

Takai, O., 222
Tanaka, J., 101
Terzini, E., 269
Tseng, B.-H., 232
Tucci, M., 269
Turek, P., 107

Vareille, J.-C., 191
Vernières, M.C., 295
Viel, P., 200

Walck, S.D., 238
Wen, X., 146
Wittmann, J.C., 207
Won, Y.H., 287

Xing, W., 282

Yang, C.Y., 66
Yokokawa, H., 101
Yoon, S.-G., 136

Zabinski, J.S., 238
Zergioti, I., 39
Zhang, Y., 89, 146
Zheng, J., 180
Zhou, K., 89, 146
Zhu, Y., 282
Ziemann, P., 122

Elsevier Science S.A.

ELSEVIER

Thin Solid Films 303 (1997) 302

thin solid films

Author Index of Volume 303

Albella, J.M., 34
Albin, S., 180
Allon-Alaluf, M., 273
Alonso, J.C., 76
Ameziane, E.L., 255
Amouroux, J., 17
Ancey, P., 1
Anderson, W.A., 94
André, J.-J., 107
Aouadi, M.S., 53
Appelbaum, J., 273
Avni, R., 17

Baclez, E., 156
Barelaud, B., 191
Bennouna, A., 255
Bhusari, D.M., 66
Bicho, A., 47
Bied-Charreton, C., 295
Boyer, A., 1
Boyer, L., 200
Brinkmann, M., 107
Burian, A., 143

Cao, W., 89, 146
Caputo, D., 269
Celerier, A., 191
Chahboun, N., 255
Chang, L.H., 94
Chaudhary, S., 128
Chen, C.K., 66
Chen, K.C., 226
Chen, K.H., 66
Chen, L.C., 66
Chuang, T.J., 66
Clarke, G.A., 53
Cobianu, C., 117
Cooper, J.B., 180
Coratger, R., 143
Cosmin, P., 117
Cosset, F., 191
Croitoru, N., 273

Dascalu, D., 117
Da Silva, L.B., 53
De Cesare, G., 269
Dessaux, O., 156
Diamant, R., 76
Ding, M., 213, 282
Dos Santos, M.P., 151

Elazhari, M.Y., 255
Erjavec, B., 4

Faure, J., 295
Fecher, G.H., 58
Fernández-Guasti, M., 76
Ferreira, I., 47
Flueraru, C., 117
Fortunato, E., 47
Fotakis, C., 39
Foucaran, A., 1
Francke, E., 17

García, M., 76
García, M.M., 34
Garnier, F., 207
Gengembre, L., 156
Giani, A., 1
Gómez-Aleixandre, C., 34
Goudmand, P., 156
Grimblot, J., 156
Grünewald, Ch., 58
Gschwind, M., 1
Guessab, S., 200
Guo, D., 282

Haidemenopoulos, G.N., 39
Han, I.-T., 264
Han, S.G., 287
Haro-Poniatowski, E., 76
Havey, K.S., 238
He, T., 213
Hesse, D., 216
Hornyak, G.L., 84
Horowitz, G., 207
Houzé, F., 200
Hozumi, A., 222
Hsieh, C.-D., 232
Huang, X., 213
Huang, Y.F., 66

Ivashchenko, A.I., 292

Jaung, G.J., 226
Jentzsch, Th., 58
Julian, B., 180
Jüpner, H.J., 58

Kang, S.Y., 287
Kashyap, S.C., 128
Kato, M., 196
Kerner, Ia.I., 292
Khedkar, S.P., 167
Kim, H.-Y., 287
Kim, K.H., 287
Kim, M.T., 173
Kim, S.H., 264
Kiosse, G.A., 292
Kleinschmidt, A., 53
Koch, T., 122
Koga, A., 101
Kwon, J.-H., 136

Laaziz, Y., 255
Lang, P., 207
Lécayon, G., 200
Lee, C.-K., 232
Lee, H.J., 287
Lee, J., 173
Lee, J.-W., 264
Lee, M.H., 287
Leray, I., 295
Li, B., 213
Li, Y., 282
Lin, M.C., 66
Liu, W., 89
Lotz, B., 207
Lu, T., 282

Maçarico, A., 47
Maccioni, E., 27
Maharizi, M., 273
Maronchuk, I.Yu., 292
Martin, C.R., 84
Martins, R., 47
Meng, L.-j., 151
Merkel, M., 58
Meyer, S., 207
Miloševv, I., 246
Minarini, C., 269
Miralaï, S.F., 17
Morrison, H., 180
Morvan, D., 17
Mosset, A., 143
Murakami, M., 277
Mutel, B., 156

Navinšek, B., 246
Newton, P., 200
Nichogi, K., 277
Nickel, H., 17
Nicolini, C., 27
Noël, S., 200
Nunes, R., 47

Oelsner, A., 58
Onishi, H., 101
Osborne, N.R., 53
Ostertag, Ch., 58
Outzourhit, A., 255

Palma, F., 269
Pandya, D.K., 128
Pansu, R., 295
Park, Y.S., 264
Parsons, R.R., 53
Pascal-Delannoy, F., 1

Radhakrishnan, S., 167
Ram, M.K., 27
Ramiro-Bargueño, J., 255

Sánchez, O., 34
Schönhense, G., 58
Seidman, A., 273
Senz, St., 216
Shao, X., 213
Shibagaki, S., 101
Shirakawa, Y., 101
Sieber, H., 216
Singh, K.J., 128
Song, P., 180
Sonoda, T., 196
Straupé, C., 207
Strehblow, H.-H., 246
Sun, G., 282

Takai, O., 222
Tanaka, J., 101
Terzini, E., 269
Tseng, B.-H., 232
Tucci, M., 269
Turek, P., 107

Vareille, J.-C., 191
Vernières, M.C., 295
Viel, P., 200

Walck, S.D., 238
Wen, X., 146
Wittmann, J.C., 207
Won, Y.H., 287

Xing, W., 282

Yang, C.Y., 66
Yokokawa, H., 101
Yoon, S.-G., 136

Zabinski, J.S., 238
Zergioti, I., 39
Zhang, Y., 89, 146
Zheng, J., 180
Zhou, K., 89, 146
Zhu, Y., 282
Ziemann, P., 122

Elsevier Science S.A.

ELSEVIER

Thin Solid Films 303 (1997) 303–306

thin solid films

Subject Index of Volume 303

Alkali metals
Circular dichroism in angular resolved photoemission from pure and Rb-doped C_{60} and $C_{22}H_{14}$ layers on platinum and tungsten, 58
Growth and stoichiometry of the Cs_xSb surface film of a high-efficiency, multialkali-antimonide photocathode, 4
Alumina membranes
Optical properties of a family of Au-nanoparticle-containing alumina membranes in which the nanoparticle shape is varied from needle-like (prolate) to spheroid, to pancake-like (oblate), 84
Amorphous materials
Investigation of amorphous silicon compensated materials over a wide range of dopant concentrations, 269
The influence of diamond-like carbon films on the properties of silicon solar cells, 273
Amorphous SiC:H films
Characterization of amorphous SiC:H films deposited from hexamethyldisilazane, 173
Antimony
Growth and stoichiometry of the Cs_xSb surface film of a high-efficiency, multialkali-antimonide photocathode, 4
Atomic force microscopy
Atomic force microscopy study of the topographic evolution of polyacrylonitrile thin films submitted to a rapid thermal treatment, 200
Highly oriented thin film of a mixed-stack charge-transfer complex, 277
In-situ growth of superconducting $YBa_2Cu_3O_{7-\delta}$ thin films at low oxygen partial pressures, 128
Observation of $Cd_{26}As_{74}$ and $Zn_{32}P_{68}$ by atomic force microscopy, 143
Atomic force microscopy (AFM)
Surface studies of chemically vapour-deposited silicon films using friction force microscopy, 117
Auger electron spectroscopy
Chemical reaction path for thin film oxidation of stainless steel, 101
Auger electron spectroscopy (AES)
Effects of ion-beam-assisted deposition on the growth of zirconia films, 122
Preparation of Pt thin films deposited by metalorganic chemical vapor deposition for ferroelectric thin films, 136

Biomaterials
Effects of discharge voltage on Ti–O film formation on Ti–6Al–4V alloy by reactive DC sputtering, 196
Bismuth
Elaboration of Bi_2Te_3 by metal organic chemical vapor deposition, 1

Capacitors
Single and multilayer ferroelectric $PbZr_xTi_{1-x}O_3$ (PZT) on $BaTiO_3$, 94
Ceramics
$LaMnO_3$ perovskite thin film deposition, from aqueous nitrate solutions of La and Mn, in a low-pressure plasma expanded through a nozzle (PETN), 17

Chemical vapour deposition
Elaboration of Bi_2Te_3 by metal organic chemical vapor deposition, 1
Preparation of ultra water-repellent films by microwave plasma-enhanced CVD, 222
Chemical vapour deposition (CVD)
Cyclic technique for the enhancement of highly oriented diamond film growth, 264
Preparation of Pt thin films deposited by metalorganic chemical vapor deposition for ferroelectric thin films, 136
Si-containing crystalline carbon nitride derived from microwave plasma-enhanced chemical vapor deposition, 66
Surface studies of chemically vapour-deposited silicon films using friction force microscopy, 117
Coatings
The influence of diamond-like carbon films on the properties of silicon solar cells, 273
Compensation
Investigation of amorphous silicon compensated materials over a wide range of dopant concentrations, 269
Conducting polymer
The electrochromic response of polyaniline and its copolymeric systems, 27
Conducting polymers
Application of dip-coating process for depositing conducting polypyrrole films, 167
Conductivity
Dimensional effect on the electrical conductivity of polycrystalline SnO_2 thin films, 292
Copolymers
The electrochromic response of polyaniline and its copolymeric systems, 27

Defect kinetics
Investigation of amorphous silicon compensated materials over a wide range of dopant concentrations, 269
Deposition process
Thin reactive LiF films for nuclear sensors, 191
Depth profiling
Effects of a titanium interlayer on the formation of platinum silicides, 232
Diamond
Cyclic technique for the enhancement of highly oriented diamond film growth, 264
Influence of oxygen on the nucleation and growth of diamond films, 34
The influence of diamond-like carbon films on the properties of silicon solar cells, 273
Dielectrics
A method for monitoring the thickness of semiconductor and dielectric thin films: application to the determination of large-area thickness profiles, 255
Single and multilayer ferroelectric $PbZr_xTi_{1-x}O_3$ (PZT) on $BaTiO_3$, 94

Elsevier Science S.A.

Diffusion
Films of polyvinylpyrrolidone containing zinc tetraphenylporphyrin: evidence for aggregation of porphyrins in the presence of pyridine, 295
Dip-coating
Application of dip-coating process for depositing conducting polypyrrole films, 167

Elastic properties
Elaboration and study of an elastic hard Si-based coating obtained at room temperature from a far cold remote nitrogen plasma, 156
Electrical properties and measurements
Fabrication and characterization of an electro-optic polymer waveguide modulator for photonic applications, 287
Highly conductive and highly transparent n-type microcrystalline silicon thin films, 47
Properties of indium tin oxide (ITO) films prepared by r.f. reactive magnetron sputtering at different pressures, 151
Structure and properties of Fe-containing polymer composite films prepared by PEMOCVD, 146
Electron energy loss spectroscopy (EELS)
Effects of ion-beam-assisted deposition on the growth of zirconia films, 122
Electronic devices
Fabrication and characterization of an electro-optic polymer waveguide modulator for photonic applications, 287
Electron microscopy
Effects of a titanium interlayer on the formation of platinum silicides, 232
Electron spin resonance
ESR study of oriented lithium phthalocyanine thin films on glass substrate, 107
Epitaxial thin films
Crystallographic orientation and morphology of epitaxial In_2O_3 thin films grown on MgO(001) single crystal substrates, 216
Epitaxy
Cyclic technique for the enhancement of highly oriented diamond film growth, 264
Sexithiophene thin films epitaxially oriented on polytetrafluoroethylene substrates: Structure and morphology, 207

Film morphology
Crystallographic orientation and morphology of epitaxial In_2O_3 thin films grown on MgO(001) single crystal substrates, 216
Fluorescence
Films of polyvinylpyrrolidone containing zinc tetraphenylporphyrin: evidence for aggregation of porphyrins in the presence of pyridine, 295
Fourier transform infrared spectroscopy (FTIR)
Surface characterization of pulsed UV-laser modified polyamide films, 180

Glow discharge
D.c. diode ion nitriding behavior of titanium and Ti–6Al–4V, 226
Glow discharge mass spectroscopy (GDMS)
$LaMnO_3$ perovskite thin film deposition, from aqueous nitrate solutions of La and Mn, in a low-pressure plasma expanded through a nozzle (PETN), 17
Glow discharge optical spectroscopy (GDOS)
$LaMnO_3$ perovskite thin film deposition, from aqueous nitrate solutions of La and Mn, in a low-pressure plasma expanded through a nozzle (PETN), 17
Growth mechanism
Growth and stoichiometry of the Cs_2Sb surface film of a high-efficiency, multialkali-antimonide photocathode, 4

Hall effect
Highly conductive and highly transparent n-type microcrystalline silicon thin films, 47
Hard coatings
Comparison of TiN, ZrN and CrN hard nitride coatings: Electrochemical and thermal oxidation, 246
Hardness
Elaboration and study of an elastic hard Si-based coating obtained at room temperature from a far cold remote nitrogen plasma, 156
Hydrocarbons
Circular dichroism in angular resolved photoemission from pure and Rb-doped C_{60} and $C_{22}H_{14}$ layers on platinum and tungsten, 58

Inconel/carbon multilayers
Inconel/carbon multilayers for X-ray mirrors, 53
Indium oxide
Properties of indium tin oxide (ITO) films prepared by r.f. reactive magnetron sputtering at different pressures, 151
In_2O_3
Crystallographic orientation and morphology of epitaxial In_2O_3 thin films grown on MgO(001) single crystal substrates, 216
Ion bombardment
Effects of ion-beam-assisted deposition on the growth of zirconia films, 122
Ionic diffusion
The electrochromic response of polyaniline and its copolymeric systems, 27
Iron
Structure and properties of Fe-containing polymer composite films prepared by PEMOCVD, 146

Langmuir–Blodgett films
Direct deposition and characterization of Langmuir–Blodgett monolayers of soluble polyimides, 282
Highly oriented thin film of a mixed-stack charge-transfer complex, 277
Lithium fluoride films
Thin reactive LiF films for nuclear sensors, 191
Luminescence
Photoluminescent thin films of terbium chloride-doped yttrium oxide deposited by the pulsed laser ablation technique, 76

Metals
D.c. diode ion nitriding behavior of titanium and Ti–6Al–4V, 226
MgO
Crystallographic orientation and morphology of epitaxial In_2O_3 thin films grown on MgO(001) single crystal substrates, 216
Microwave plasma
Preparation of ultra water-repellent films by microwave plasma-enhanced CVD, 222

NbN thin films
The chemistry, structure, and resulting wear properties of magnetron-sputtered NbN thin films, 238
Nickel carbonyl
Structure and tribological properties of plasma-polymerized nickel carbonyl films, 89
Nitrides
Comparison of TiN, ZrN and CrN hard nitride coatings: Electrochemical and thermal oxidation, 246
D.c. diode ion nitriding behavior of titanium and Ti–6Al–4V, 226
Si-containing crystalline carbon nitride derived from microwave plasma-enhanced chemical vapor deposition, 66

Optical properties
A method for monitoring the thickness of semiconductor and dielectric thin films: application to the determination of large-area thickness profiles, 255

Fabrication and characterization of an electro-optic polymer waveguide modulator for photonic applications, 287
Optical properties of a family of Au-nanoparticle-containing alumina membranes in which the nanoparticle shape is varied from needle-like (prolate) to spheroid, to pancake-like (oblate), 84
Red color filter in an organo-soluble polyamide matrix for liquid crystal displays, 213
Sexithiophene thin films epitaxially oriented on polytetrafluoroethylene substrates: Structure and morphology, 207
Optical spectroscopy
Films of polyvinylpyrrolidone containing zinc tetraphenylporphyrin: evidence for aggregation of porphyrins in the presence of pyridine, 295
Organic substances
Circular dichroism in angular resolved photoemission from pure and Rb-doped C_{60} and $C_{22}H_{14}$ layers on platinum and tungsten, 58
ESR study of oriented lithium phthalocyanine thin films on glass substrate, 107
Highly oriented thin film of a mixed-stack charge-transfer complex, 277
Organometallic vapour deposition
Dimensional effect on the electrical conductivity of polycrystalline SnO_2 thin films, 292
Preparation of Pt thin films deposited by metalorganic chemical vapor deposition for ferroelectric thin films, 136
Oxidation
Comparison of TiN, ZrN and CrN hard nitride coatings: Electrochemical and thermal oxidation, 246
Oxides
Chemical reaction path for thin film oxidation of stainless steel, 101

Photoelectron spectroscopy
Circular dichroism in angular resolved photoemission from pure and Rb-doped C_{60} and $C_{22}H_{14}$ layers on platinum and tungsten, 58
Physical vapour deposition (PVD)
Comparison of TiN, ZrN and CrN hard nitride coatings: Electrochemical and thermal oxidation, 246
Plasma processing and deposition
Effects of discharge voltage on Ti–O film formation on Ti–6Al–4V alloy by reactive DC sputtering, 196
Elaboration and study of an elastic hard Si-based coating obtained at room temperature from a far cold remote nitrogen plasma, 156
Influence of oxygen on the nucleation and growth of diamond films, 34
Structure and properties of Fe-containing polymer composite films prepared by PEMOCVD, 146
Structure and tribological properties of plasma-polymerized nickel carbonyl films, 89
Polyacrylonitrile thin films
Atomic force microscopy study of the topographic evolution of polyacrylonitrile thin films submitted to a rapid thermal treatment, 200
Polyamide films
Surface characterization of pulsed UV-laser modified polyamide films, 180
Polyaniline
The electrochromic response of polyaniline and its copolymeric systems, 27
Polymers
Direct deposition and characterization of Langmuir–Blodgett monolayers of soluble polyimides, 282
Fabrication and characterization of an electro-optic polymer waveguide modulator for photonic applications, 287
Films of polyvinylpyrrolidone containing zinc tetraphenylporphyrin: evidence for aggregation of porphyrins in the presence of pyridine, 295
Red color filter in an organo-soluble polyamide matrix for liquid crystal displays, 213
Polypyrrole
Application of dip-coating process for depositing conducting polypyrrole films, 167
PTFE
Sexithiophene thin films epitaxially oriented on polytetrafluoroethylene substrates: Structure and morphology, 207
Pulsed laser deposition
Growth of TiB_2 and TiC coatings using pulsed laser deposition, 39

Raman scattering
Highly conductive and highly transparent n-type microcrystalline silicon thin films, 47

Scanning electron microscopy
Cyclic technique for the enhancement of highly oriented diamond film growth, 264
Preparation of Pt thin films deposited by metalorganic chemical vapor deposition for ferroelectric thin films, 136
Semiconductors
A method for monitoring the thickness of semiconductor and dielectric thin films: application to the determination of large-area thickness profiles, 255
ESR study of oriented lithium phthalocyanine thin films on glass substrate, 107
Observation of $Cd_{26}As_{74}$ and $Zn_{32}P_{68}$ by atomic force microscopy, 143
Sensors
Dimensional effect on the electrical conductivity of polycrystalline SnO_2 thin films, 292
Silicides
Effects of a titanium interlayer on the formation of platinum silicides, 232
Silicon
Highly conductive and highly transparent n-type microcrystalline silicon thin films, 47
Surface studies of chemically vapour-deposited silicon films using friction force microscopy, 117
Silicon nitride
Elaboration and study of an elastic hard Si-based coating obtained at room temperature from a far cold remote nitrogen plasma, 156
Solar cells
The influence of diamond-like carbon films on the properties of silicon solar cells, 273
Sputtering
Effects of discharge voltage on Ti–O film formation on Ti–6Al–4V alloy by reactive DC sputtering, 196
Effects of ion-beam-assisted deposition on the growth of zirconia films, 122
In-situ growth of superconducting $YBa_2Cu_3O_{7-\delta}$ thin films at low oxygen partial pressures, 128
Properties of indium tin oxide (ITO) films prepared by r.f. reactive magnetron sputtering at different pressures, 151
Single and multilayer ferroelectric $PbZr_xTi_{1-x}O_3$ (PZT) on $BaTiO_3$, 94
Structural properties
Growth of TiB_2 and TiC coatings using pulsed laser deposition, 39
Properties of indium tin oxide (ITO) films prepared by r.f. reactive magnetron sputtering at different pressures, 151
Structure and properties of Fe-containing polymer composite films prepared by PEMOCVD, 146
Structure and tribological properties of plasma-polymerized nickel carbonyl films, 89
The chemistry, structure, and resulting wear properties of magnetron-sputtered NbN thin films, 238
The electrochromic response of polyaniline and its copolymeric systems, 27

Superconductivity
In-situ growth of superconducting $YBa_2Cu_3O_{7-\delta}$ thin films at low oxygen partial pressures, 128
Surface composition
Growth and stoichiometry of the Cs_xSb surface film of a high-efficiency, multialkali-antimonide photocathode, 4
Surface defects
A method for monitoring the thickness of semiconductor and dielectric thin films: application to the determination of large-area thickness profiles, 255
Surface morphology
In-situ growth of superconducting $YBa_2Cu_3O_{7-\delta}$ thin films at low oxygen partial pressures, 128
Surface pressure
Direct deposition and characterization of Langmuir–Blodgett monolayers of soluble polyimides, 282
Surface roughness
Surface studies of chemically vapour-deposited silicon films using friction force microscopy, 117

Tellurium
Elaboration of Bi_2Te_3 by metal organic chemical vapor deposition, 1
Thin films
Application of dip-coating process for depositing conducting polypyrrole films, 167
Tin oxide
Dimensional effect on the electrical conductivity of polycrystalline SnO_2 thin films, 292
Titanium nitride
D.c. diode ion nitriding behavior of titanium and Ti–6Al–4V, 226
Titanium oxide
Effects of discharge voltage on Ti–O film formation on Ti–6Al–4V alloy by reactive DC sputtering, 196
Transmission electron microscopy (TEM)
Si-containing crystalline carbon nitride derived from microwave plasma-enhanced chemical vapor deposition, 66
Transmission electron microscopy
Crystallographic orientation and morphology of epitaxial In_2O_3 thin films grown on MgO(001) single crystal substrates, 216
Tribology
Structure and tribological properties of plasma-polymerized nickel carbonyl films, 89

Ultra water repellency
Preparation of ultra water-repellent films by microwave plasma-enhanced CVD, 222

Valence band
Comparison of TiN, ZrN and CrN hard nitride coatings: Electrochemical and thermal oxidation, 246

X-ray photoelectron spectroscopy (XPS)
Comparison of TiN, ZrN and CrN hard nitride coatings: Electrochemical and thermal oxidation, 246
Si-containing crystalline carbon nitride derived from microwave plasma-enhanced chemical vapor deposition, 66
X-ray diffraction
Crystallographic orientation and morphology of epitaxial In_2O_3 thin films grown on MgO(001) single crystal substrates, 216
Effects of a titanium interlayer on the formation of platinum silicides, 232
X-ray mirrors
Inconel/carbon multilayers for X-ray mirrors, 53
X-ray scattering
Direct deposition and characterization of Langmuir–Blodgett monolayers of soluble polyimides, 282

Young's modulus
Characterization of amorphous SiC:H films deposited from hexamethyldisilazane, 173
Yttrium oxide
Photoluminescent thin films of terbium chloride-doped yttrium oxide deposited by the pulsed laser ablation technique, 76